

Summary of 2017 beam test results with BTL sensors

Timing days

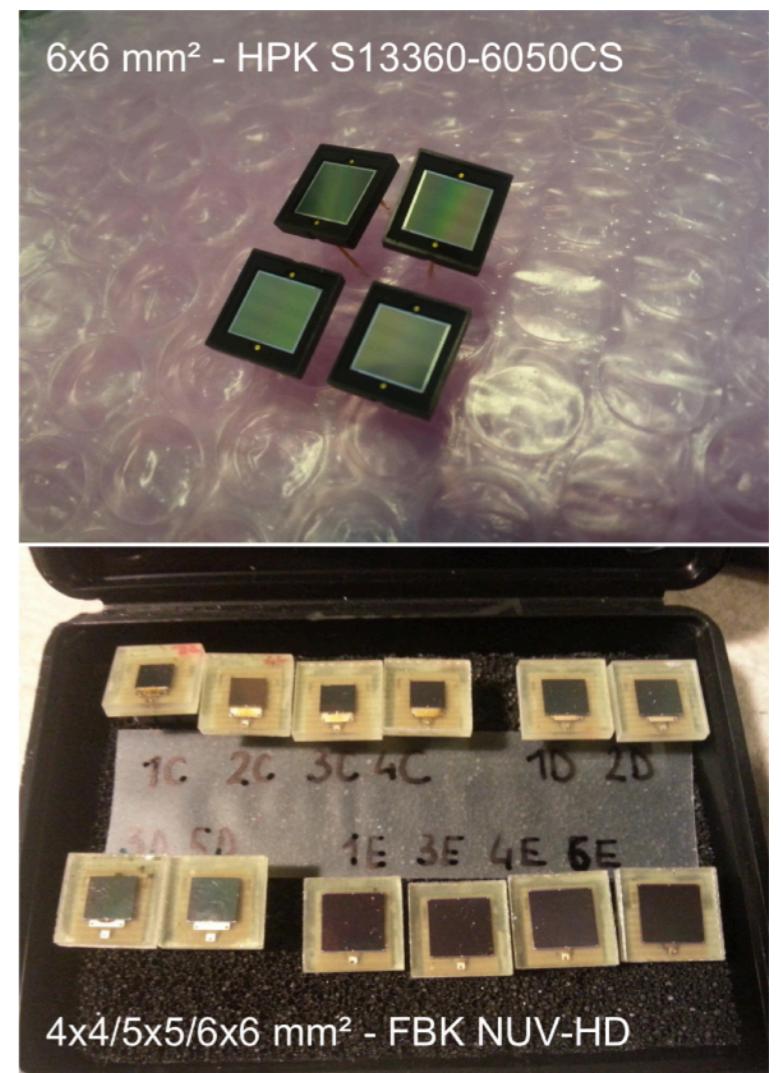
October 31st, 2017

A. Benaglia, with the contribution of many

INFN Milano-Bicocca

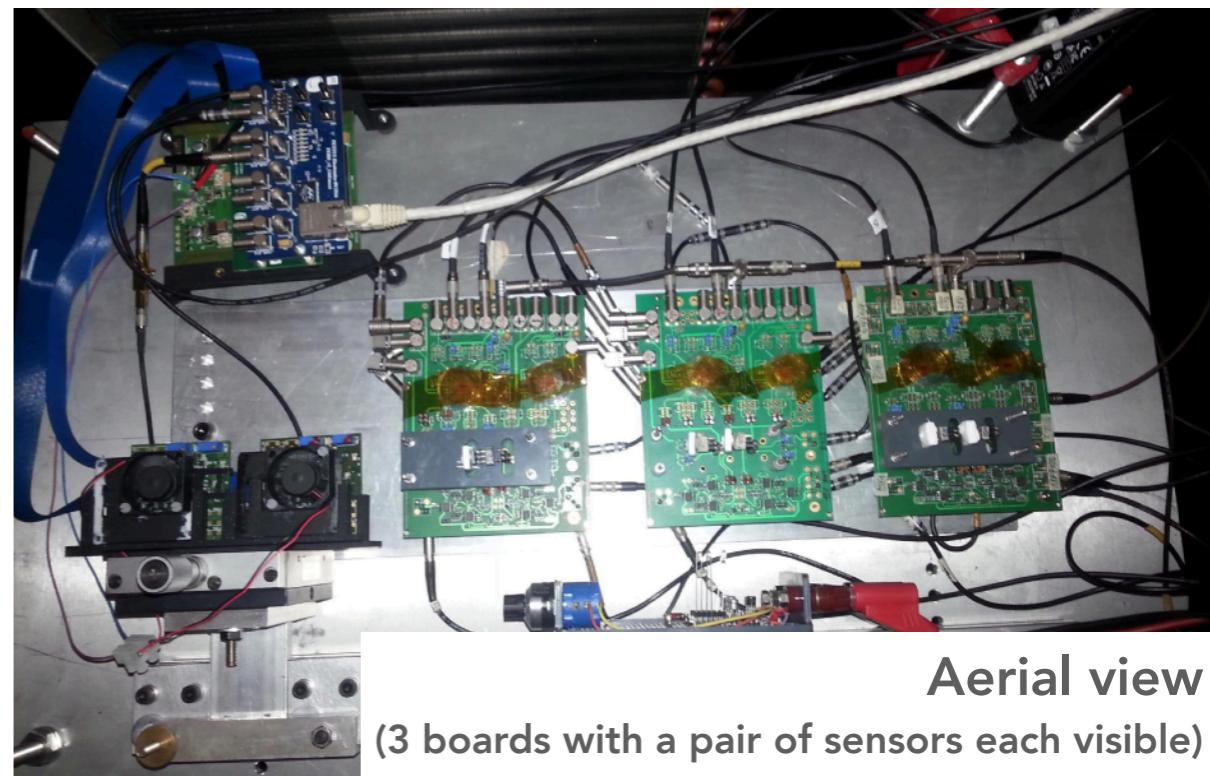
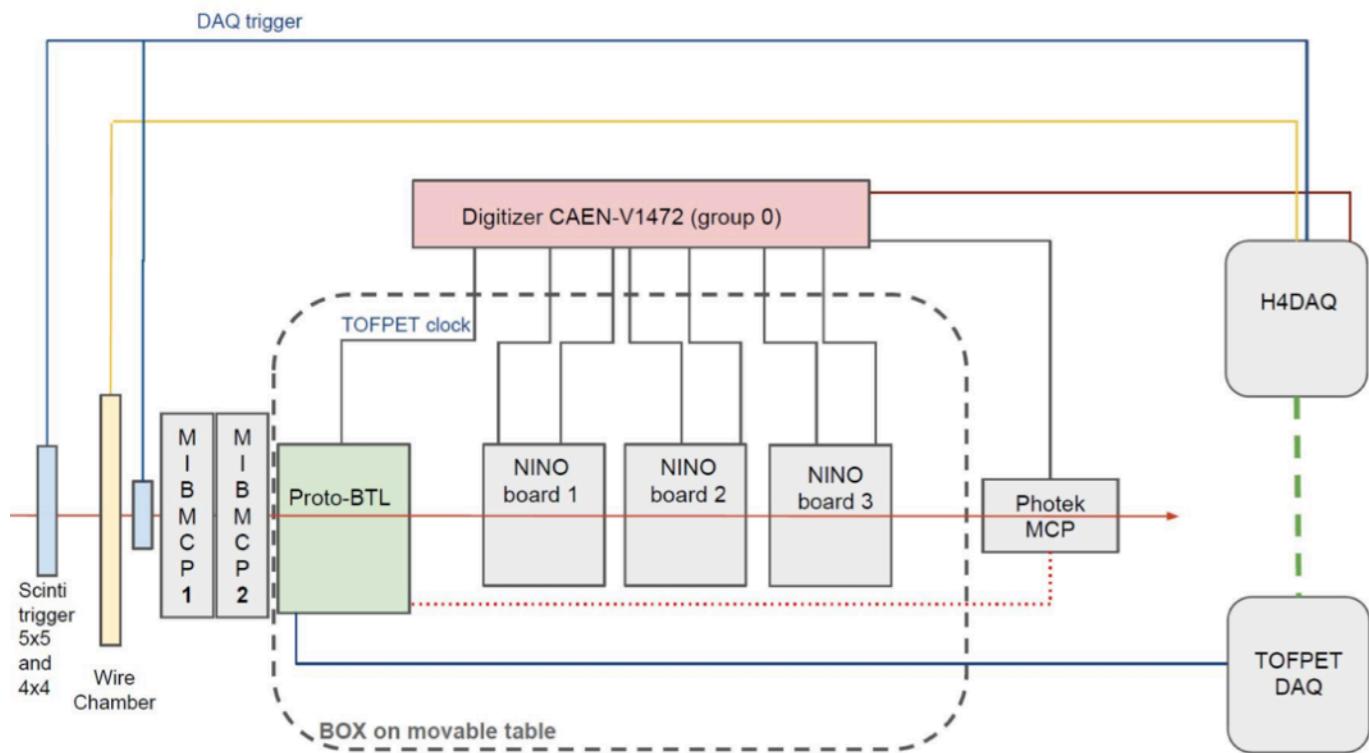
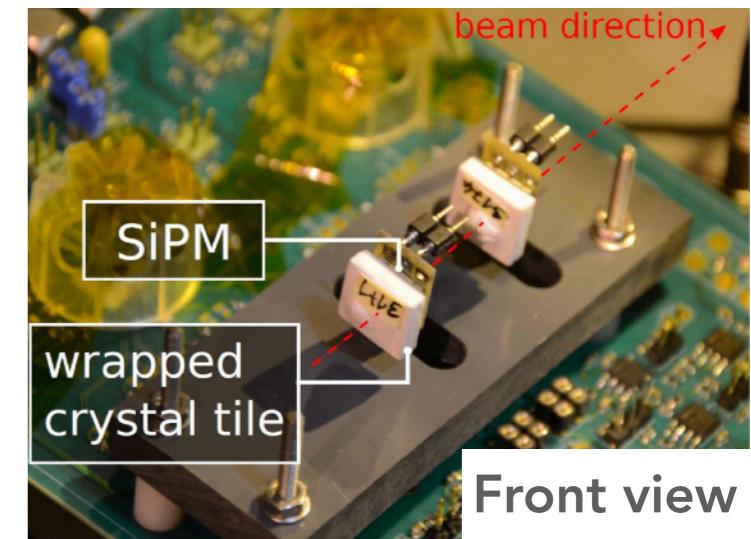
The 2017 beam tests

- Three beam test campaigns in 2017:
 - T9 beam line (May)
 - H4 beam line (July)
 - H6 beam line (August)
- Purpose: optimization of the individual sensors
 - systematic study of several **LYSO tile geometries**; **11×11×3.75 mm³** is the current default in the TP
 - » different crystal surfaces (5.6×5.6 mm², 10×10 mm², and 12×12 mm² also tested)
 - » different thickness tested too (2, 3, 4 mm)
 - systematic study and **characterization of SiPMs** (in terms of active surface, PDE, cell size); a sensor with **4×4 mm²** total surface, **≤ 15 μm cell size**, and operated at **1-2 V** above breakdown is the current default
 - » many different devices from different vendors tested



The typical beam test setup

- Time from LYSO+SiPM extracted with a **dedicated ASIC** providing **leading edge** discriminator (a.k.a. NINO)
- **Analog SiPM signal** also extracted for **amplitude** measurement
- **External precise time** reference provided by one or multiple **MCPs** (not present in all beam tests)
- All signals **digitized** with CAEN-V1742



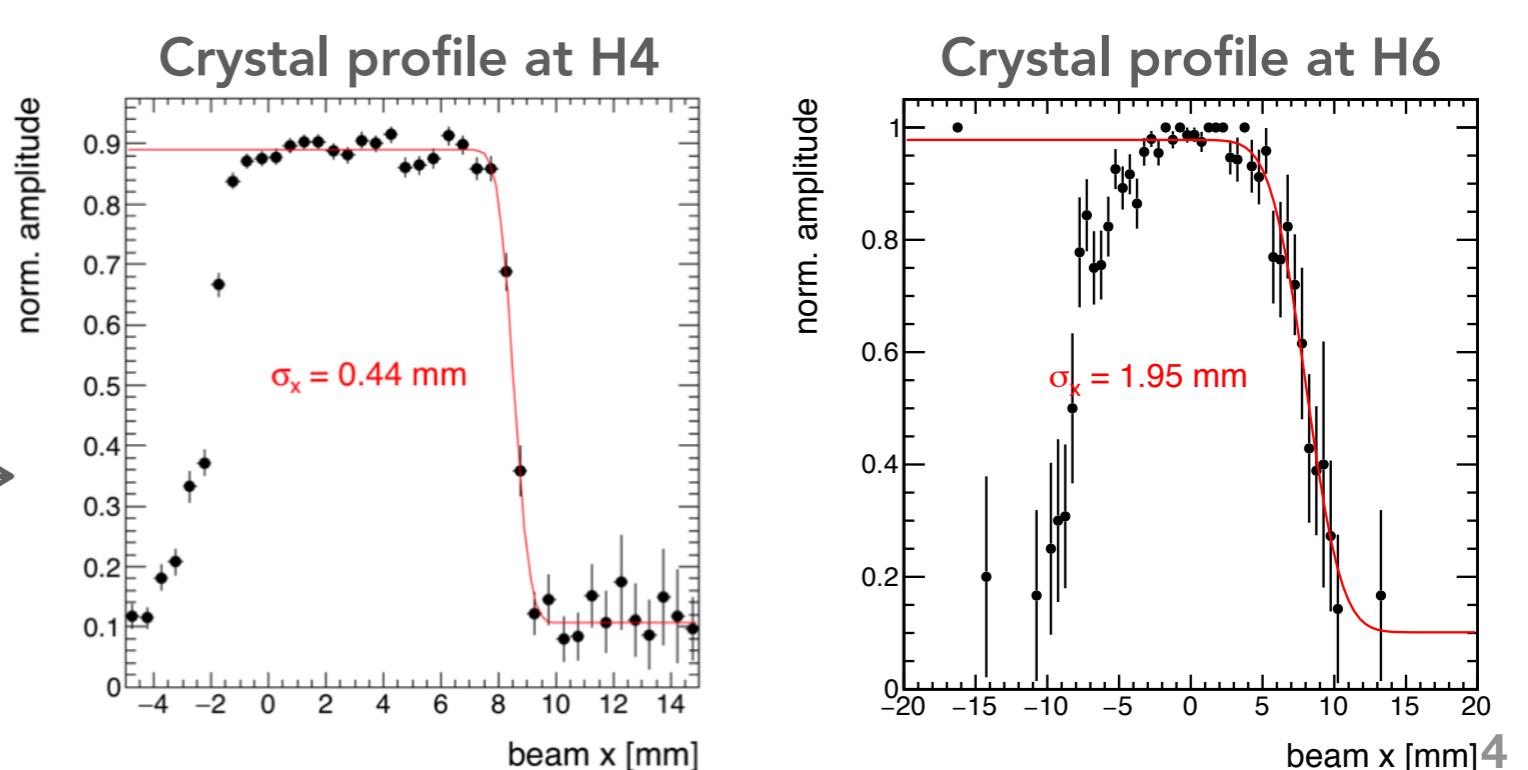
See Adi's talk for a discussion on proto-MTD module data acquired with TOFPET-2 ASIC

Time response dependence on impact point

- A most important result of the beam tests was the study of the time response **dependence** on the **impact point position** on the crystal surface
- Two conditions are necessary for this measurement:
 - presence of an **external time reference** ($\Delta t = t_{\text{LYSO+SiPM}} - t_{\text{MCP}}$), as opposed to comparing two aligned crystals ($\Delta t = t_{\text{LYSO+SiPM1}} - t_{\text{LYSO+SiPM2}}$)
 - particle tracking with **good spatial resolution** and **parallel beam**
 - the combination of both was not always realized at TB

- MCP not well aligned with sensors at H4
- no position information at T9
- divergent beam at **H6 (~2 mm res.)**

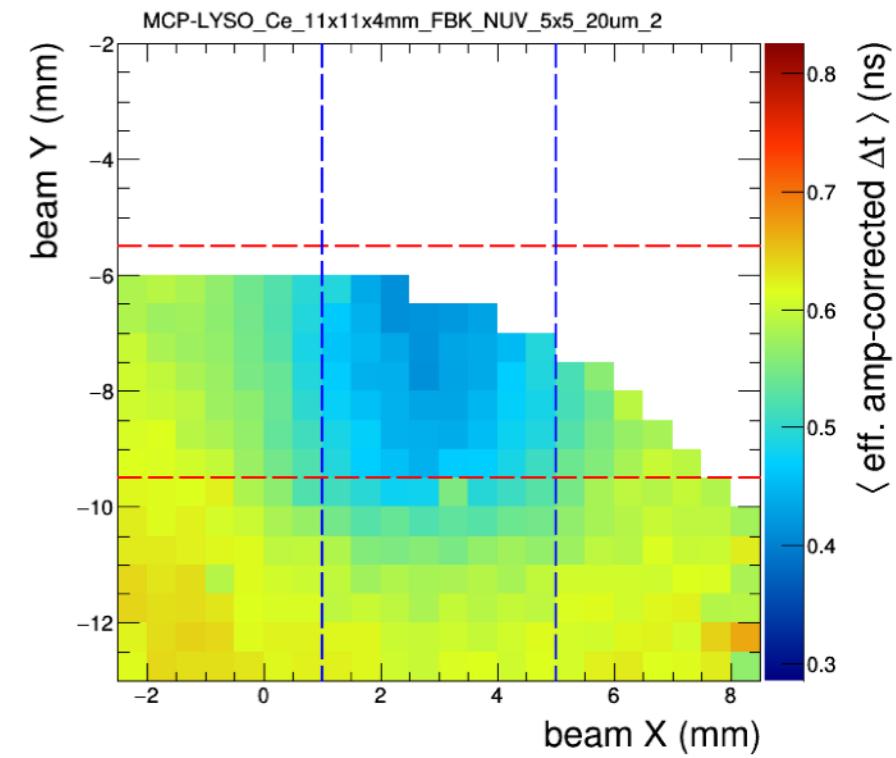
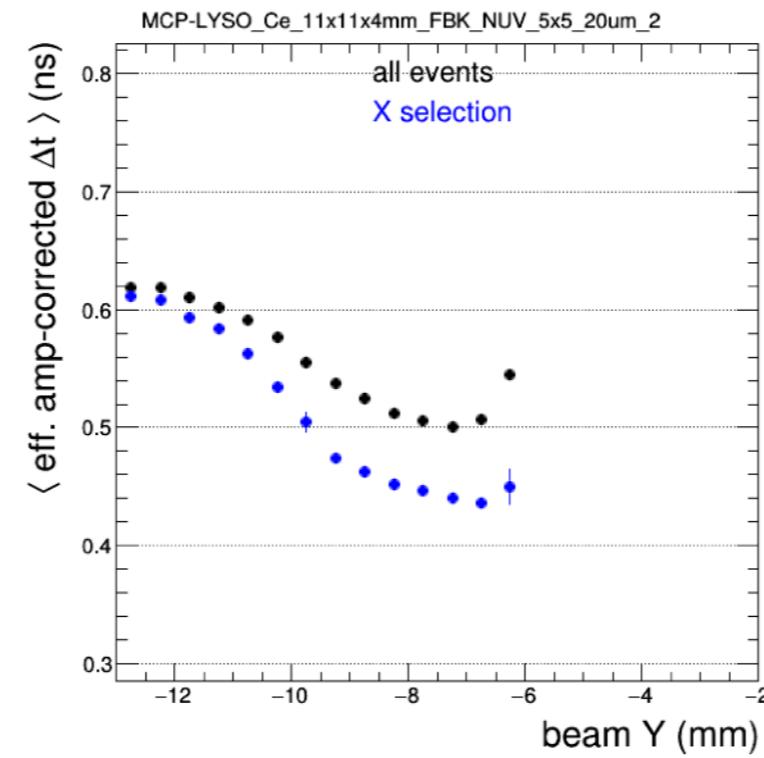
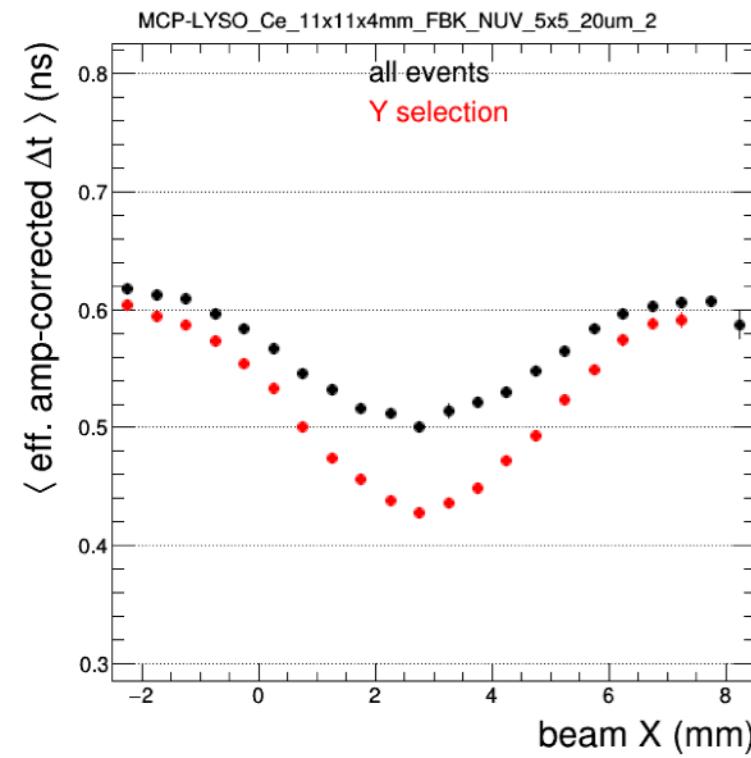
- H4 experimental setup was good enough to allow the uniformity study
 - MIP impact point position resolution at **H4 ~0.5 mm**



Time response dependence on impact point

- A critical dependence of the time response on the impact point position on the crystal surface was revealed
 - **O(200 ps) response delay** for events impinging outside the SiPM region w.r.t. central events
- The effect is cancelled (to a certain extent) when two aligned crystals are compared for the measurement

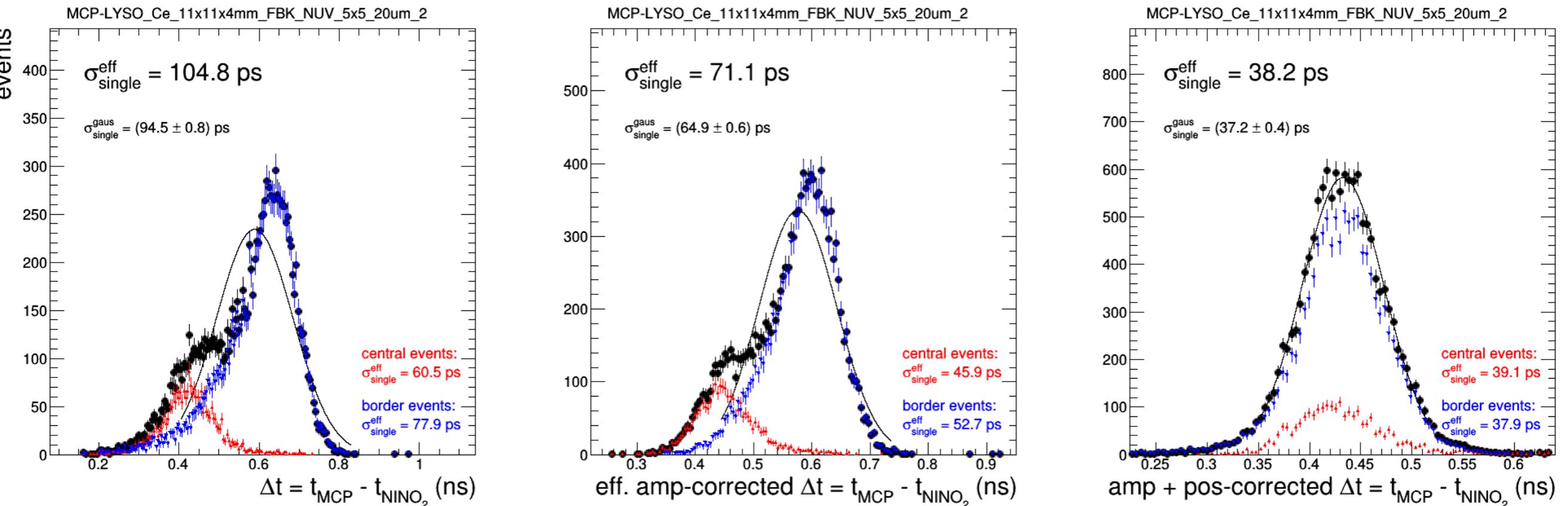
SiPM: FBK-NUV 5×5 mm²
Crystal: LYSO 11×11×4 mm³



Time response dependence on impact point

- If not accounted for, the response non uniformity has a critical effect on time resolution
 - no position correction $\Rightarrow \mathcal{O}(60 \text{ ps})$ added in quadrature

SiPM: FBK-NUV 5×5 mm² 20 μm, 33 V (6 OV)
Crystal: LYSO 11×11×4 mm³



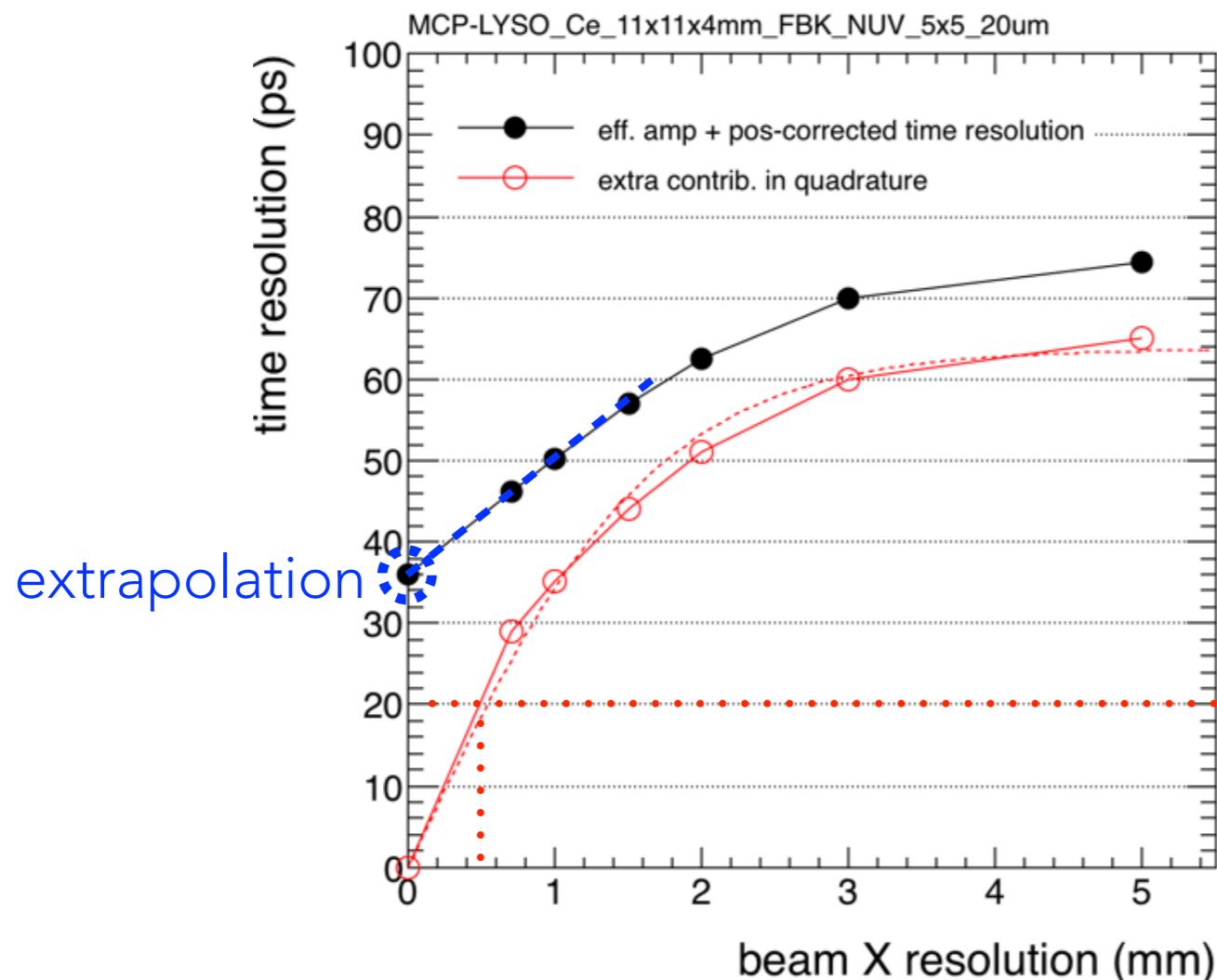
no corrections
two populations visible
(central-border events)

time-walk corrections
two populations visible
(central-border events)

time-walk + position
corrections

Position resolution required

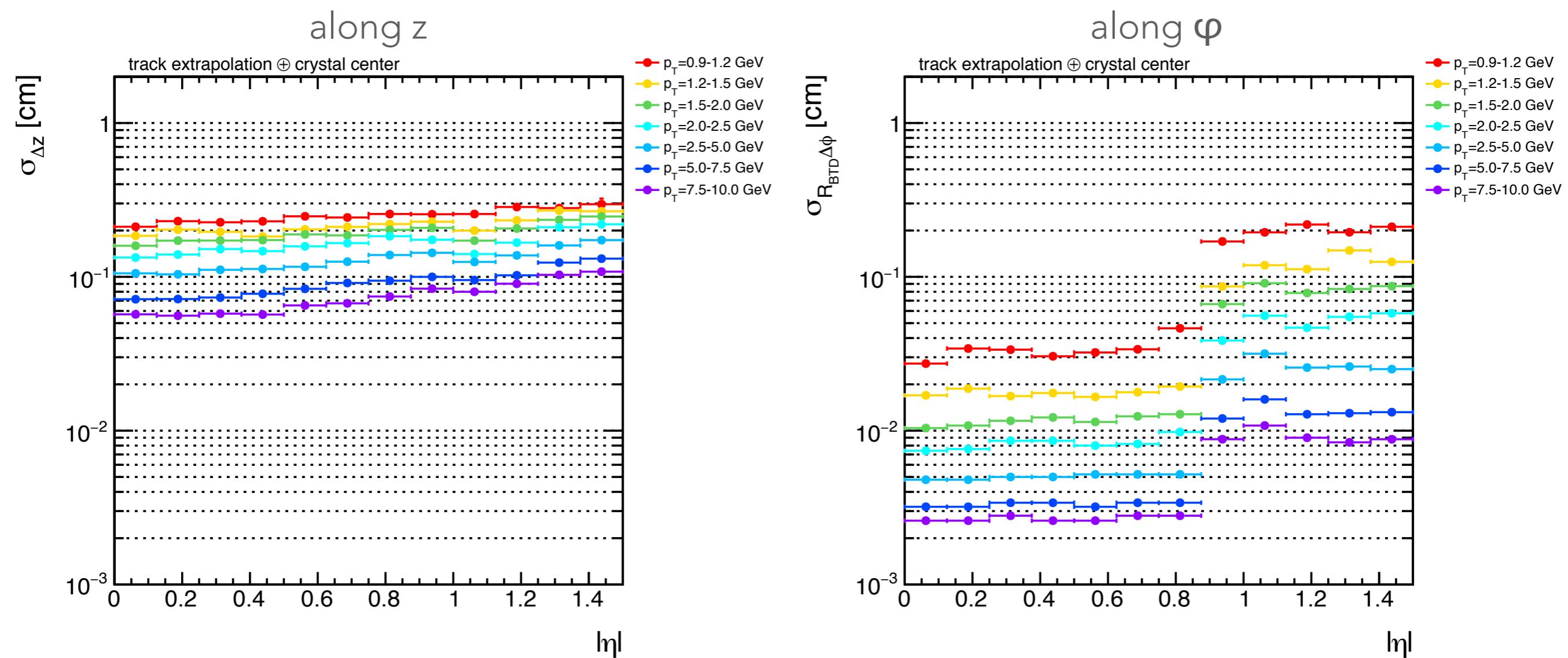
- MIP impact point position smeared in TB data to assess the level of precision required
 - N.B. position resolution at H4 was ~0.5 mm
 - time resolution for 0 position resolution extrapolated from nearby points



sub-millimiter precision needed
to limit the extra-smearing from
non-uniformity below 30 ps

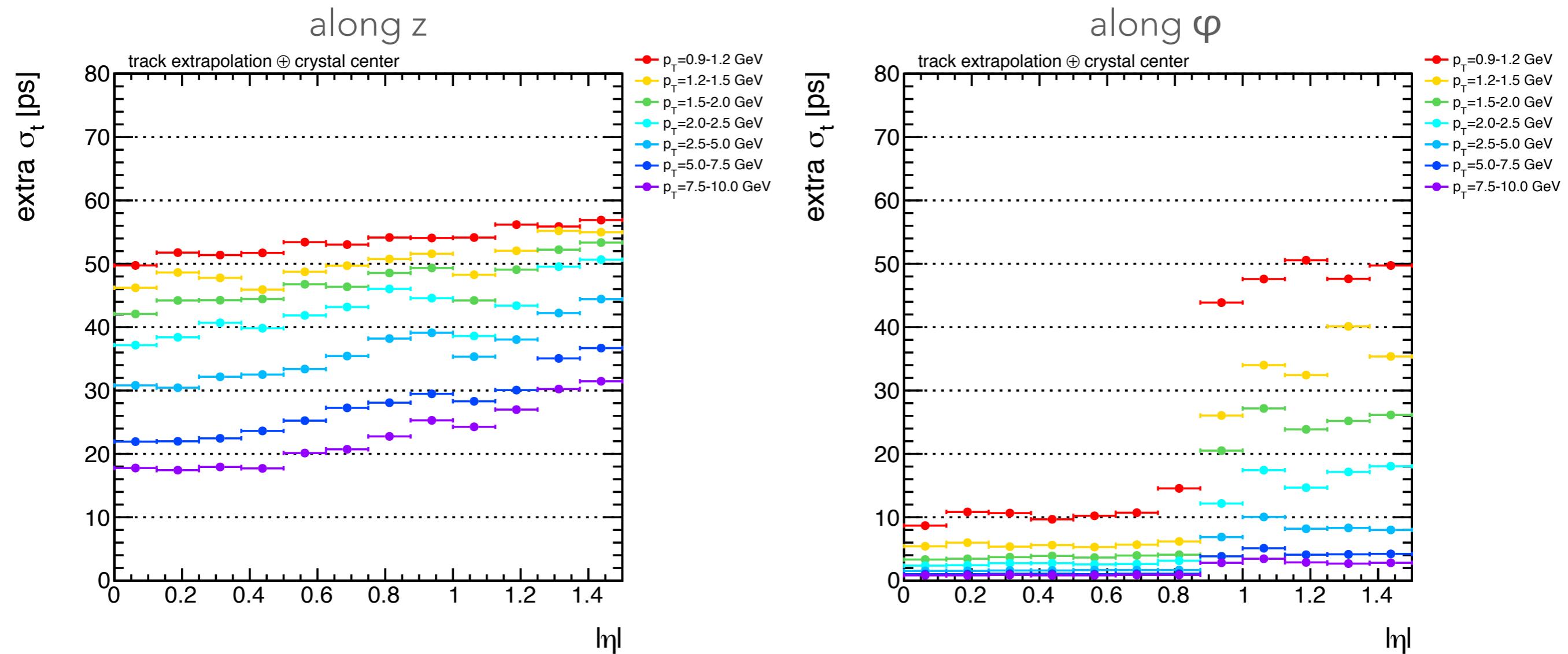
Impact point resolution in the MTD

- Resolution on track extrapolation from the outermost hit to the MTD \oplus crystal center position (CMS Phasell geometry simulation)
 - combination with crystal center recovers resolution when tracker only is worse than crystal size / $\sqrt{12} = \sim 3$ mm



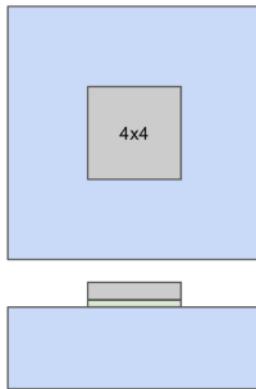
Impact point resolution in the MTD

- Time resolution extra-smearing from limited knowledge of impact point:
 - critical degradation of performance along z
 - critical degradation of performance along φ below 2 GeV and for $|\eta| > 1$
- This calls for a **robust hardware solution**



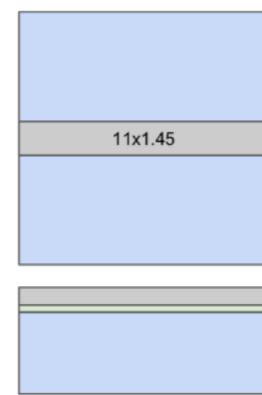
Possible hardware solutions

- Different options being considered to reduce the light collection non-uniformity (won't discuss them extensively here):



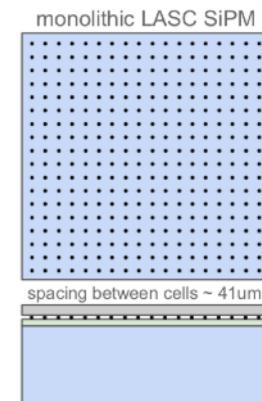
default

1 4×4 mm² in the center



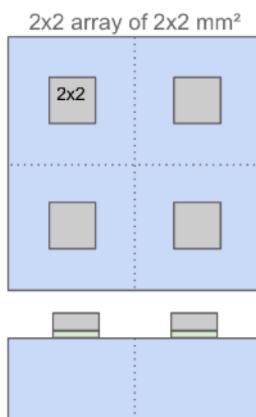
SiPM strip

cancel non-unif. in one direction (z)



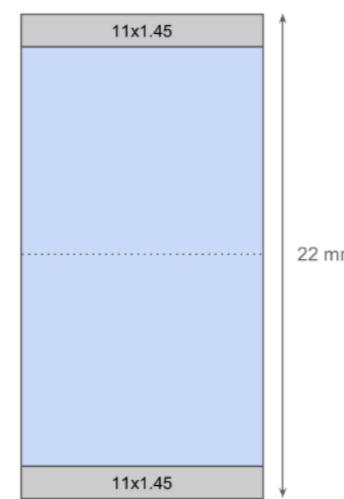
"Final" solution

full tile readout with a sparse cell SiPM



array

multiple smaller SiPMs

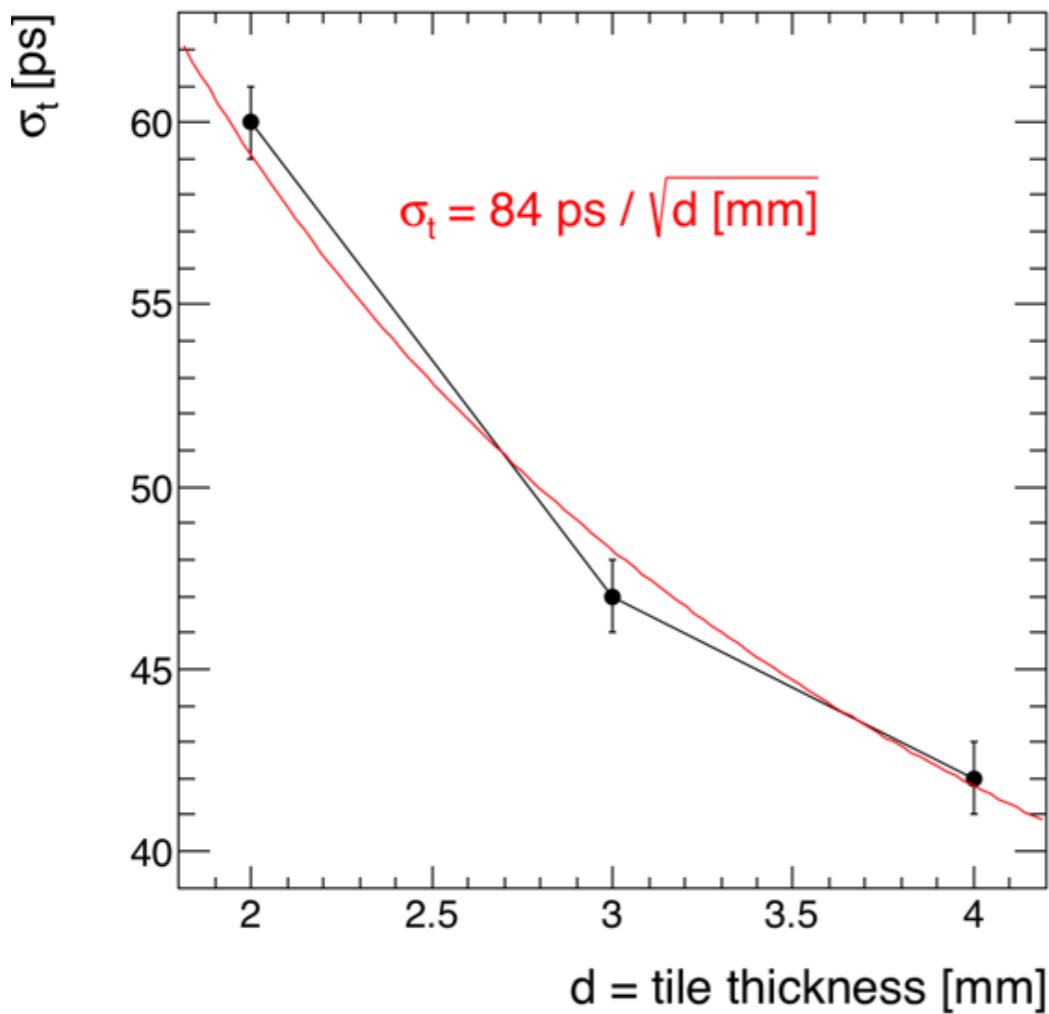


Double readout

time difference at the two ends

Scaling with thickness

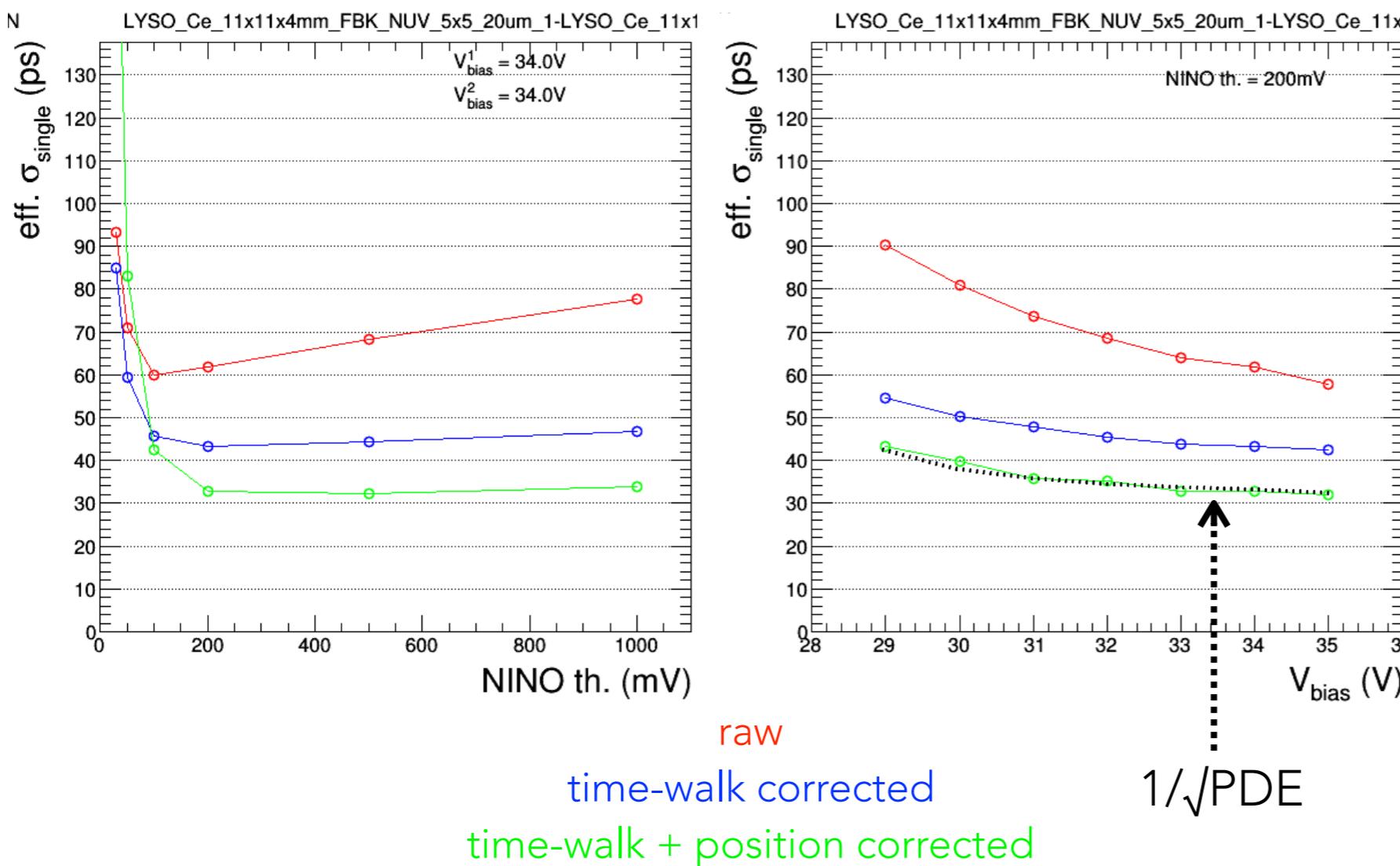
- [T9 beam test]
 - LYSO tiles of different **thickness** ($11 \times 11 \times 2 \text{ mm}^3$, $11 \times 11 \times 3 \text{ mm}^3$, $11 \times 11 \times 4 \text{ mm}^3$) tested
 - SiPM Ketek $3 \times 3 \text{ mm}^2$ $25 \mu\text{m}$
 - time resolution measured **comparing two identical sensors**



- time resolution scales as $1/\sqrt{d}$, as light output (LO) scales as d
- **40-45 ps** for the nominal MTD thickness

Scaling with PDE

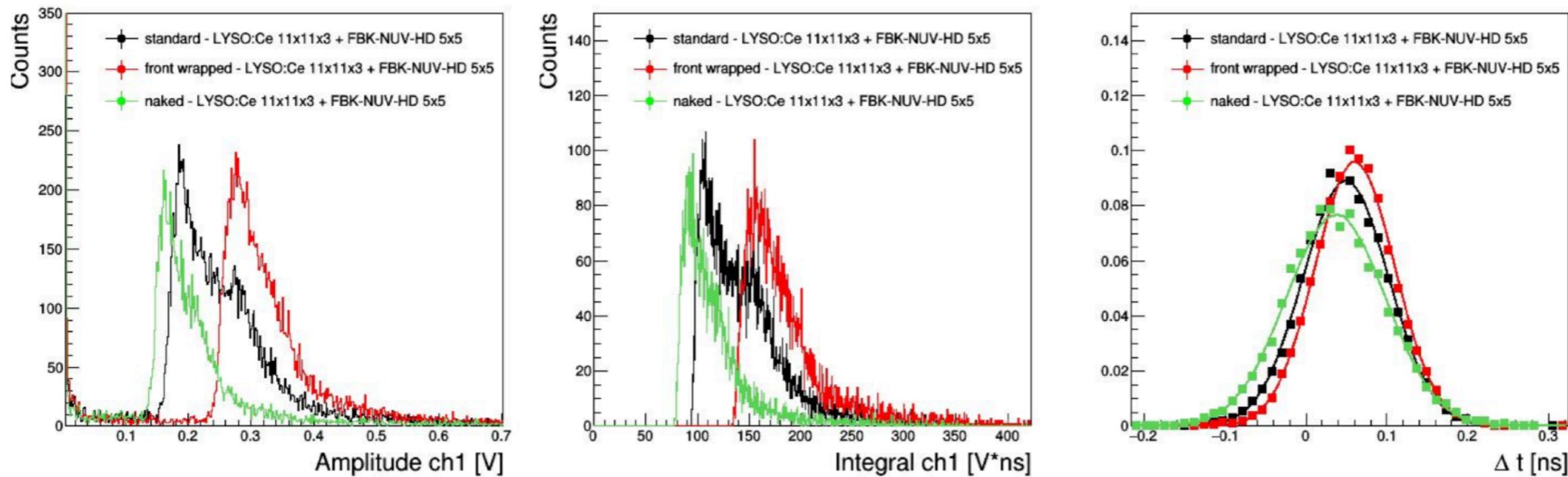
- [H4 beam test]
 - 11×11×4 mm³ LYSO tile
 - SiPM FBK-NUV 5×5 mm² 20 μm
 - time resolution measured **comparing two identical sensors**



- fully corrected time resolution flat vs. NINO threshold above 100-200 mV
- time resolutions scales as $1/\sqrt{\text{PDE}}$
- **30-35 ps** for 4-5 V overvoltage

Effect of wrapping

- [H4 beam test]
 - 11×11×3 mm³ LYSO tile, different **wrappings** (no wrapping, rear+lateral sides, all sides)
 - SiPM FBK-NUV 5×5 mm² 20 µm
 - time resolution measured **comparing two identical sensors**



34V/200 mV - no BS selection	Max. Amp. MPV [V]	Pulse Integral MPV [V*ns]	σ_t single (uncorr., corr.) [ps]
no wrapping (ch1/ch2)	0.17 / 0.18	96 / 104	61.9 / 42.9
rear+side wrapping (ch1/ch2)	0.21 / 0.24	119 / 133	53.5 / 36.6
full wrapping (ch1/ch2)	0.28 / 0.32	159 / 180	49.9 / 34.4

15 μm sensor

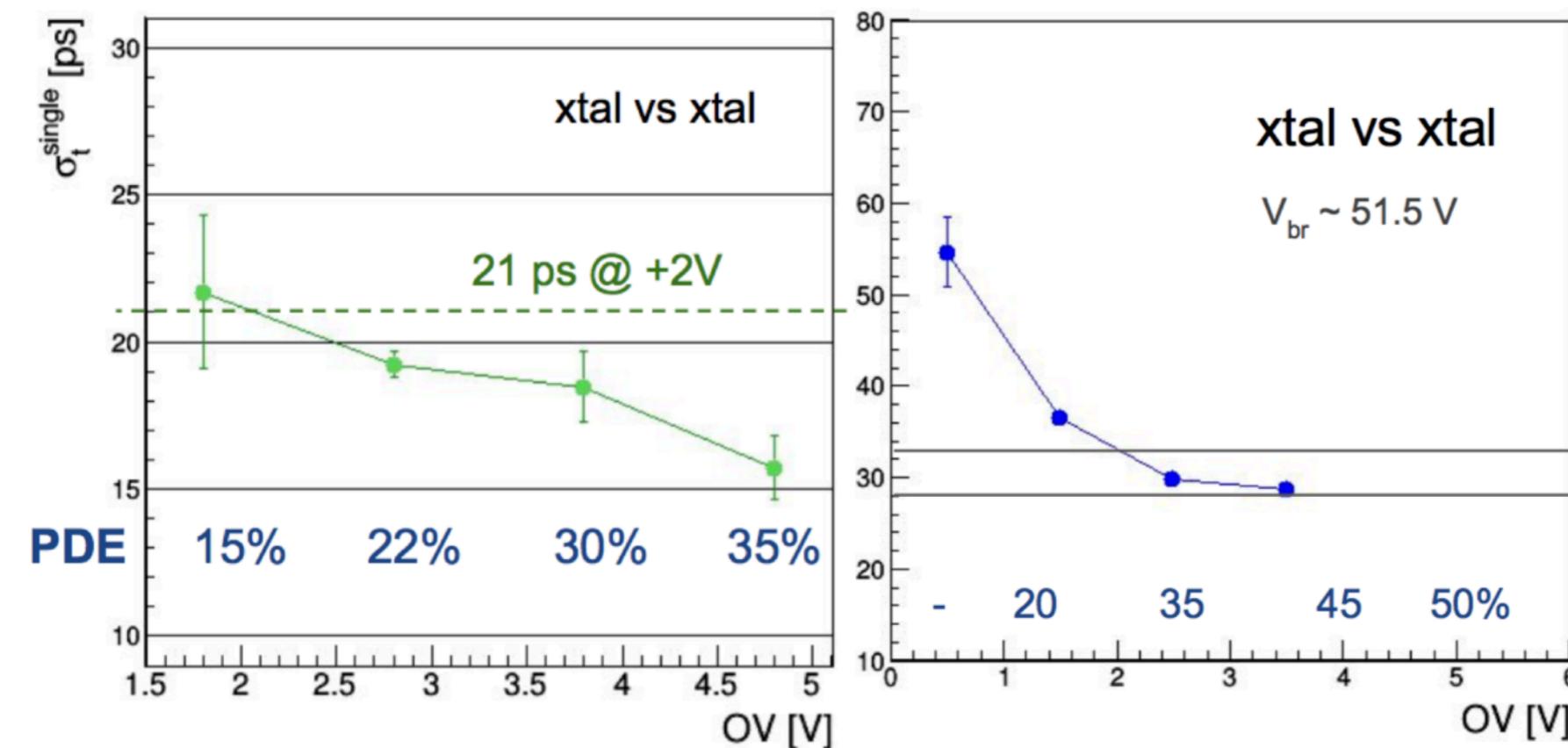
- [H6 beam test]
 - 2 \times 2 \times 3 mm³ and 5.6 \times 5.6 \times 3 mm³ LYSO tile
 - SiPM HPK 3 \times 3 mm² 15 μm : **first test of a 15 μm sensor**
 - time resolution measured **comparing two identical sensors**

small pixel (full readout)

2x2x3 LYSO + 3x3 HPK 15 μm

1/4th of a nominal MTD tile

5.6x5.6x3 LYSO + 3x3 HPK 50 μm

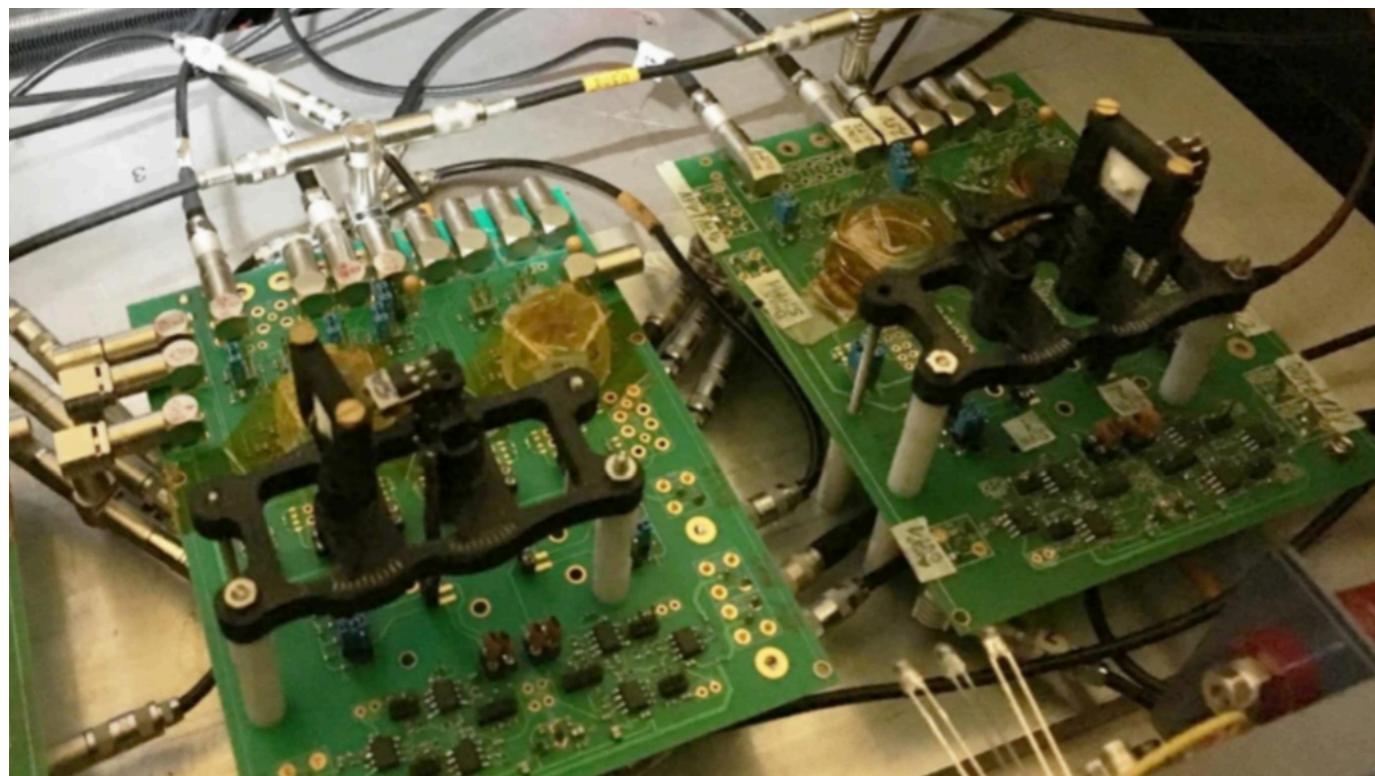


- very good time resolution when full readout of the surface — maximum light output (LO)
- time resolutions scales as $1/\sqrt{\text{PDE}}$ and as $1/\sqrt{\text{LO}}$
- ~35 ps extrapolated for a 2 \times 2 mm² sensor

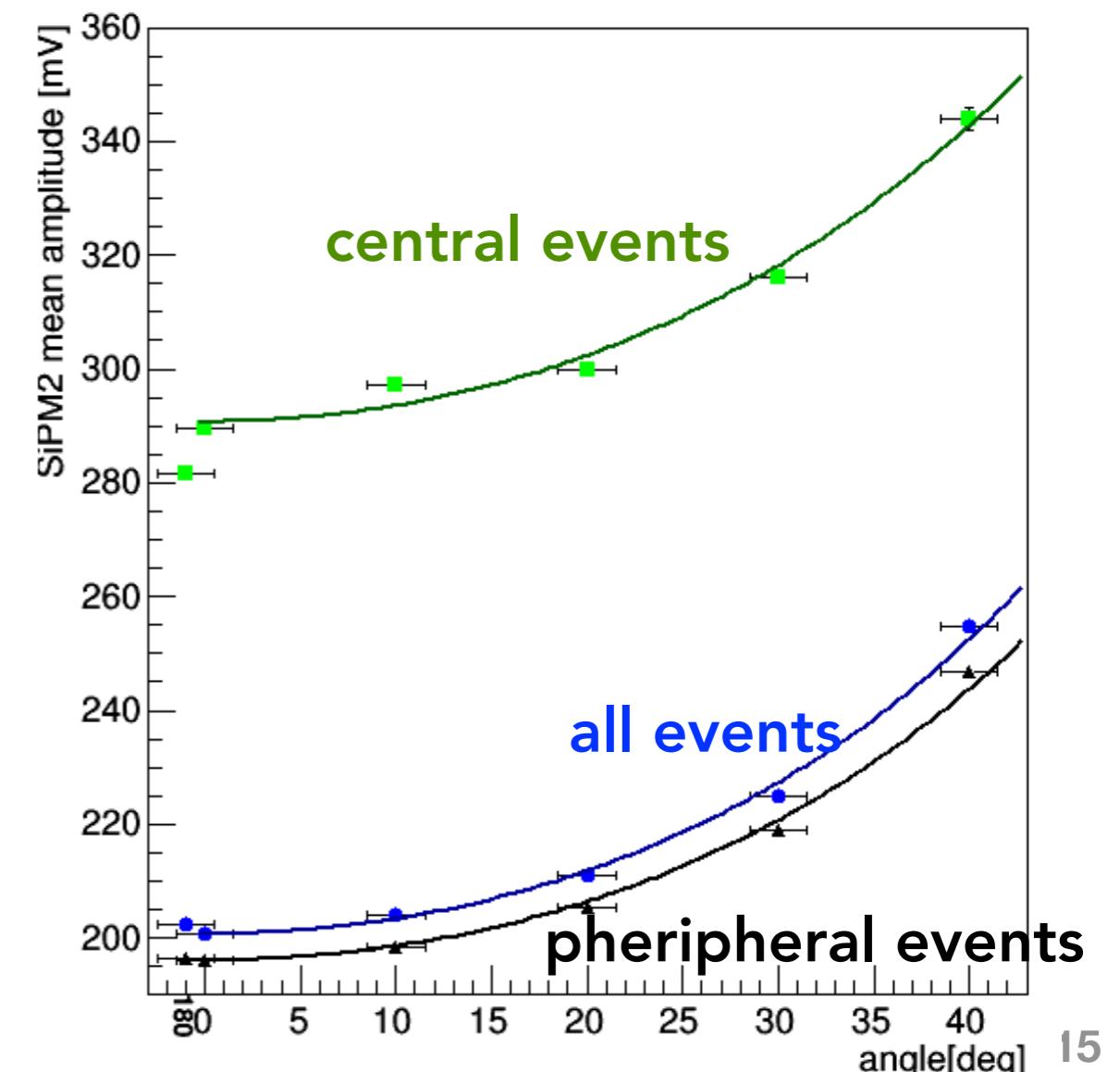
Study at different angles of incidence

- The energy deposited in the crystals by MIPs has a $d/\cos\theta$ dependence, as expected
 - this supports the η -dependent material leveling being considered in the TP

crystals tilted along x from 0 to 40°

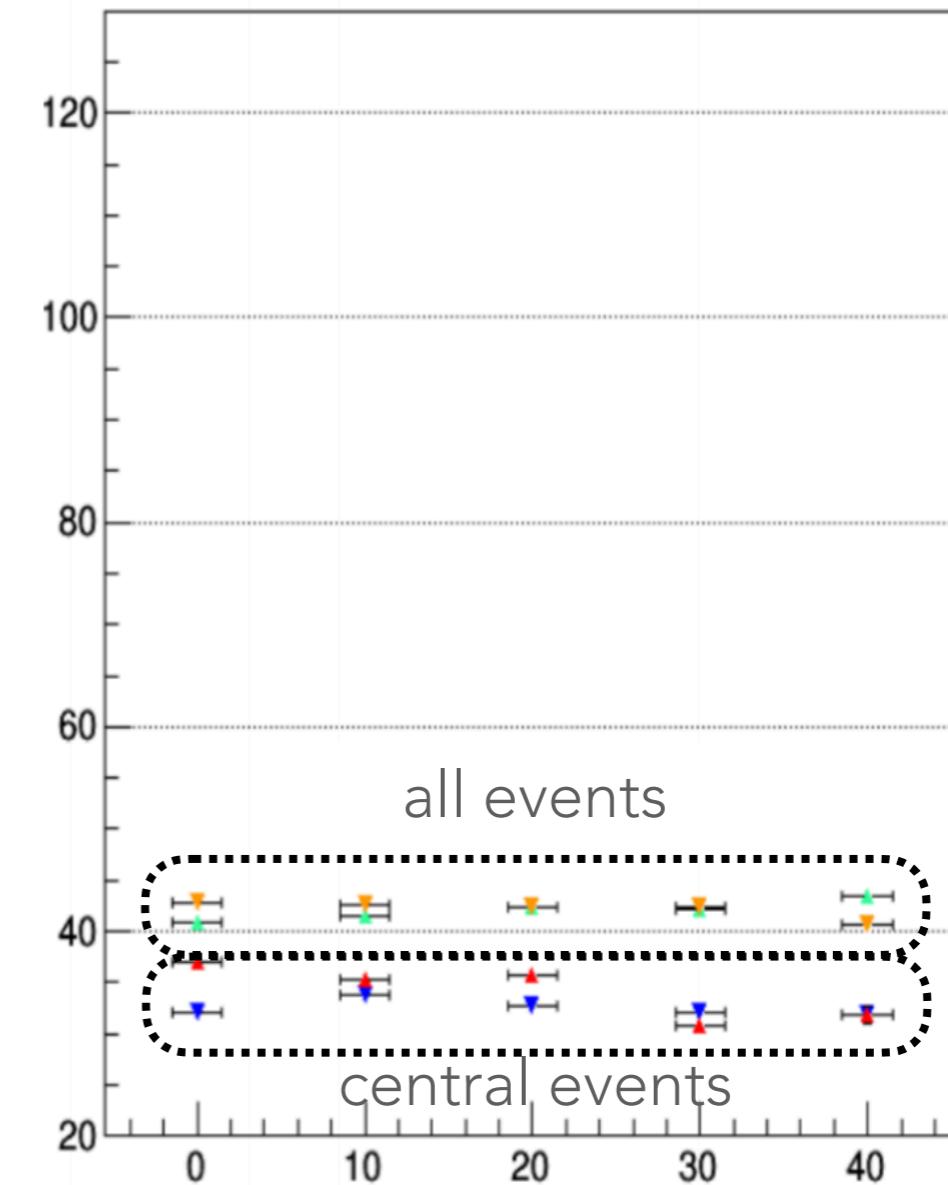
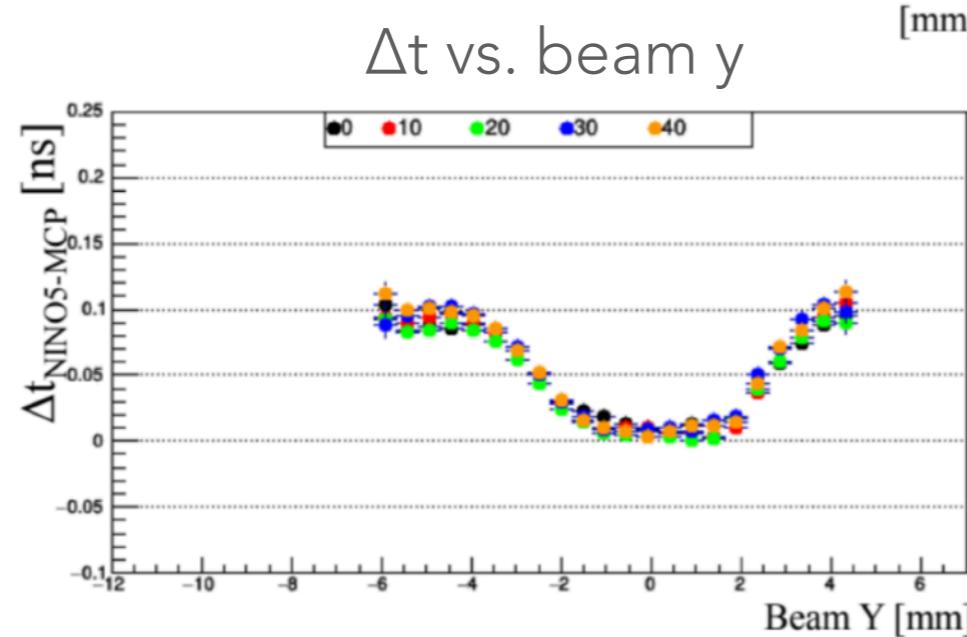
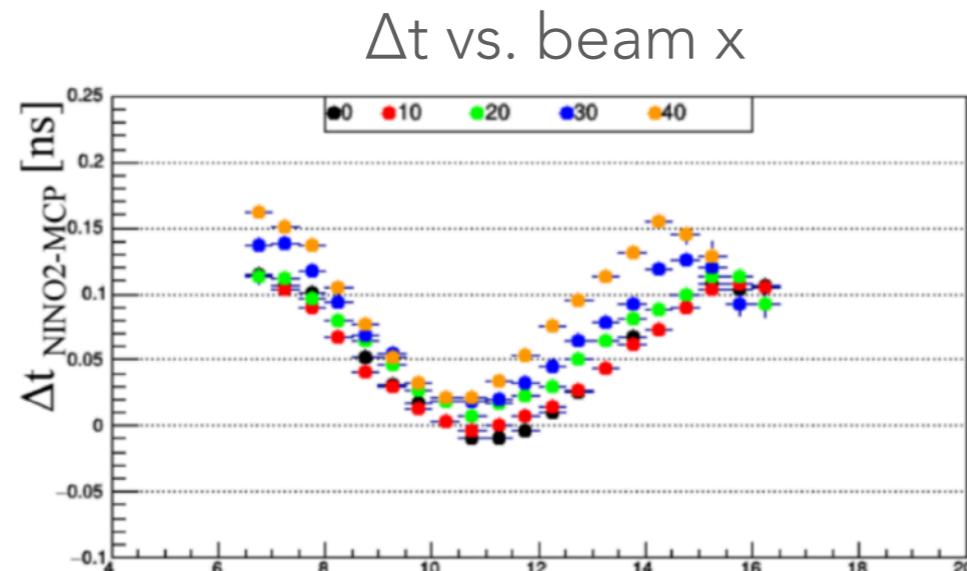


Signal amplitude variation
with slant thickness



Study at different angles of incidence

- Time resolution (measured vs. MCP) not influenced (neither negatively nor positively) by incidence angle
 - cannot exclude a residual contribution from non-uniformity
 - should plan a **test of tilted tiles of reduced thickness** in the future (as in the TP)



Summary

- 2017 beam tests have been a big effort in terms of organization, setup and data analysis. A lot of important information was collected to help steer the R&D for the next year
 - (re)discovered that performance is dominated by **light collection**:
 - » **non-uniformities** in light collection induces a **large dependence on the impact point** — a 60 ps effect if not accounted for
 - » scaling as a function of SiPM PDE, crystal thickness and fraction of crystal surface coverage confirm this
 - options to improve uniformity of light collection at the hardware level being worked on
 - optimize wrapping
 - for **future** beam tests, we need to **equip ourselves** with **instrumentation** to allow precise **particle tracking** (e.g. a pair of hodoscopes in our usual experimental box)
 - baseline result: **FBK-NUV 5×5 mm², 20 μm, 4-5 V OV** on **LYSO 11×11×4 mm³**
~33 ps (crystal-vs-crystal) / **~40 ps (MCP-vs-crystal)**
consistent with O(20 ps) extra-smearing from $\sigma_{\text{position}} \sim 0.5 \text{ mm}$